



Schunk Carbon Technology Ceramic protection against wear and tear in extreme temperatures

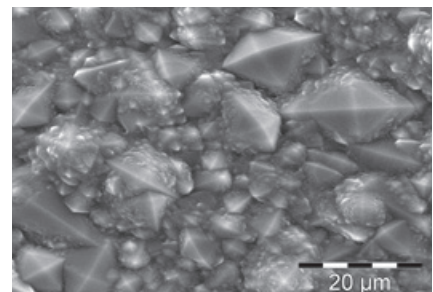
CVD processes have been used for years in the coating and hardening of tools and carbide metals.

The process has also proved to be successful for large-scale components in the chemical industry and in furnace and plant construction - the ceramic coating extends the service life and significantly increases the operating temperature of components in the process technology. CVD SiC coatings maintain temperatures from -60 to 1,600°C.

SiC properties:

- ▮ Density: 3.2 g/m³
- ▮ Hardness: < 9 according to Mohs

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*SEM image
of a SiC surface*



Schunk Group - Your coatings expert

Schunk Carbon Technology offers the complete process chain, from the production of graphite and CFC materials through mechanical post-processing of the components to purification and coating.

We manage dimensions up to 1650 mm diameter and 2000 mm height.

We refine your components with

- ▮ Chemical purification
- ▮ Coatings using the CVD process
 - ▮ CVD SiC
 - ▮ CVD Pyrographite
 - ▮ CVD Diamond

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*Heat exchanger made of graphite
with CVD SiC coating*



The Schunk Group is an internationally operating technology company. It offers a broad spectrum of products and services in the fields of carbon technology and ceramics, environment simulation and air conditioning technology, sintered metal and ultrasonic welding. The Schunk Group has bundled its expertise in the development, manufacture and application of carbon and ceramic solutions in the Schunk Carbon Technology Division.

Did we spark your interest?

We will gladly assist you with further information.

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